## **AMENDMENTS TO THE CLAIMS**

A detailed listing of all claims that are, or were, in the present application, irrespective of whether the claim(s) remains under examination in the application are presented below. The claims are presented in ascending order and each includes one status identifier. Those claims not cancelled or withdrawn but amended by the current amendment utilize the following notations for amendment: 1. deleted matter is shown by strikethrough; and 2. added matter is shown by underlining.

1-72. (Canceled).

Please add new claims 73-124 as follows:

- 73. (New) An insulating substrate board for a semiconductor comprising:
  - a ceramic substrate board; and
  - a metal alloy layer consisting essentially of aluminum of not less than 98% by weight and of silicon of not less than 0.2% by weight,

wherein the metal alloy layer is bonded on at least one surface portion of the ceramic substrate board, and wherein a Vickers hardness of the metal alloy layer is not less than 25 and not more than 35.

74. (New) The insulating substrate board according to claim 73, wherein the metal alloy layer is bonded on at least one surface portion of the ceramic substrate board by direct bonding.

- 75. (New) The insulating substrate board according to claim 73, wherein the metal alloy layer is bonded on at least one surface portion of the ceramic substrate board through a brazing material layer.
- 76. (New) An insulating substrate board for a semiconductor comprising:
  - a ceramic substrate board; and
  - a metal alloy layer consisting essentially of aluminum, silicon of about 0.6% by weight, and Mn of about 1.5% by weight,

wherein the metal alloy layer is bonded by direct bonding on at least one surface portion of the ceramic substrate board, and wherein a Vickers hardness of the metal alloy layer is not less than 25 and not more than 35.

- 77. (New) An insulating substrate board for a semiconductor comprising:
  - a ceramic substrate board; and
  - a metal alloy layer consisting essentially of aluminum, silicon of not less than 0.1% by weight and not more than 0.4% by weight, and Mg of not less than 0.5% by weight and not more than 1% by weight,

- 78. (New) The insulating substrate board according to claim 77, wherein the metal alloy layer is bonded on at least one surface portion of the ceramic substrate board by direct bonding.
- 79. (New) The insulating substrate board according to claim 77, wherein the metal alloy layer is bonded on at least one surface portion of the ceramic substrate board through a brazing material layer.
- 80. (New) An insulating substrate board for a semiconductor comprising:
  - a ceramic substrate board; and
  - a metal alloy layer consisting essentially of aluminum and of Mn of not less than 0.2% by weight and not more than 2% by weight,

- 81. (New) The insulating substrate board according to claim 80, wherein the metal alloy layer is bonded on at least one surface portion of the ceramic substrate board by direct bonding.
- 82. (New) The insulating substrate board according to claim 80, wherein the metal alloy layer is bonded on at least one surface portion of the ceramic substrate board through a brazing material layer.

- 83. (New) An insulating substrate board for a semiconductor comprising:
  - a ceramic substrate board; and
  - a metal alloy layer consisting essentially of aluminum and of Cu of not less than 1.0% by weight and not more than 2.0% by weight,

wherein the metal alloy layer is bonded on at least one surface portion of the ceramic substrate board, and wherein a Vickers hardness of the metal alloy layer is not less than 25 and not more than 35.

- 84. (New) The insulating substrate board according to claim 83, wherein the metal alloy layer is bonded on at least one surface portion of the ceramic substrate board by direct bonding.
- 85. (New) The insulating substrate board according to claim 83, wherein the metal alloy layer is bonded on at least one surface portion of the ceramic substrate board through a brazing material layer.
- 86. (New) An insulating substrate board for a semiconductor comprising:
  - a ceramic substrate board; and
  - a metal alloy layer consisting essentially of aluminum and of Zn of about 2.0% by weight,

- 87. (New) The insulating substrate board according to claim 86, wherein the metal alloy layer is bonded on at least one surface portion of the ceramic substrate board by direct bonding.
- 88. (New) The insulating substrate board according to claim 86, wherein the metal alloy layer is bonded on at least one surface portion of the ceramic substrate board through a brazing material layer.
- 89. (New) An insulating substrate board for a semiconductor comprising:
  - a ceramic substrate board; and
  - a metal alloy layer consisting essentially of aluminum and of Ni of about 0.5% by weight,

- 90. (New) The insulating substrate board according to claim 89, wherein the metal alloy layer is bonded on at least one surface portion of the ceramic substrate board by direct bonding.
- 91. (New) The insulating substrate board according to claim 89, wherein the metal alloy layer is bonded on at least one surface portion of the ceramic substrate board through a brazing material layer.

- 92. (New) An insulating substrate board for a semiconductor comprising:
  - a ceramic substrate board; and
  - a metal alloy layer consisting essentially of aluminum and of Mg of not less than 0.2% by weight and not more than 0.5% by weight,

wherein the metal alloy layer is bonded through a brazing material layer on at least one surface portion of the ceramic substrate board, and wherein a Vickers hardness of the metal alloy layer is not less than 25 and not more than 35.

- 93. (New) An insulating substrate board for a semiconductor comprising:
  - a ceramic substrate board; and
  - a metal alloy layer consisting essentially of aluminum, silicon of about 0.1% by weight, and Cu of about 1.0% by weight,

wherein the metal alloy layer is bonded on at least one surface portion of the ceramic substrate board, and wherein a Vickers hardness of the metal alloy layer is not less than 25 and not more than 35.

94. (New) The insulating substrate board according to claim 93, wherein the metal alloy layer is bonded on at least one surface portion of the ceramic substrate board by direct bonding.

- 95. (New) The insulating substrate board according to claim 93, wherein the metal alloy layer is bonded on at least one surface portion of the ceramic substrate board through a brazing material layer.
- 96. (New) An insulating substrate board for a semiconductor comprising:
  - a ceramic substrate board; and
  - a metal alloy layer consisting essentially of aluminum, Si of about 0.1% by weight, Cu of about 1.0% by weight, and Mg of about 0.1% by weight,

wherein the metal alloy layer is bonded on at least one surface portion of the ceramic substrate board, and wherein a Vickers hardness of the metal alloy layer is not less than 25 and not more than 35.

- 97. (New) The insulating substrate board according to claim 96, wherein the metal alloy layer is bonded on at least one surface portion of the ceramic substrate board by direct bonding.
- 98. (New) The insulating substrate board according to claim 96, wherein the metal alloy layer is bonded on at least one surface portion of the ceramic substrate board through a brazing material layer.
- 99. (New) A power module comprising:

a ceramic substrate board;

metal alloy layers consisting essentially of aluminum of not less than 98% by weight and of silicon of not less than 0.2% by weight and not more than 2% by weight, wherein the metal alloy layers are bonded on both surfaces of the ceramic substrate board;

a metal base plate bonded to one of the metal alloy layers; and

a semiconductor tip formed on the other of the metal alloy layer,

wherein a Vickers hardness of the metal alloy layer is not less than 25 and not more than 35.

- 100. (New) The power module according to claim 99, wherein the metal alloy layers are bonded on the ceramic substrate board by direct bonding.
- 101. (New) The power module according to claim 99, wherein the metal alloy layers are bonded on the ceramic substrate board through a brazing material layer.
- 102. (New) A power module comprising:

a ceramic substrate board;

metal alloy layers consisting essentially of aluminum, silicon of about 0.6% by weight, and Mn of about 1.5% by weight, wherein the metal alloy layers are bonded on both surfaces of the ceramic substrate board;

a metal base plate bonded to one of the metal alloy layers; and a semiconductor tip formed on the other of the metal alloy layer,

wherein a Vickers hardness of the metal alloy layer is not less than 25 and not more than 35.

103. (New) A power module comprising:

a ceramic substrate board;

metal alloy layers consisting essentially of aluminum, silicon of not less than 0.1% by weight and not more than 0.4% by weight, and Mg of not less than 0.5% by weight and not more than 1% by weight, wherein the metal alloy layers are bonded on both surfaces of the ceramic substrate board;

a metal base plate bonded to one of the metal alloy layers; and

a semiconductor tip formed on the other of the metal alloy layer,

wherein a Vickers hardness of the metal alloy layer is not less than 25 and not more than 35.

- 104. (New) The power module according to claim 103, wherein the metal alloy layers are bonded on the ceramic substrate board by direct bonding.
- 105. (New) The power module according to claim 103, wherein the metal alloy layers are bonded on the ceramic substrate board through a brazing material layer.
- 106. (New) A power module comprising:
  a ceramic substrate board;

metal alloy layers consisting essentially of aluminum and of Mn of not less than 0.2% by weight and not more than 2% by weight, wherein the metal alloy layers are bonded on both surfaces of the ceramic substrate board;

a metal base plate bonded to one of the metal alloy layers; and a semiconductor tip formed on the other of the metal alloy layer,

wherein a Vickers hardness of the metal alloy layer is not less than 25 and not more than

35.

- 107. (New) The power module according to claim 106, wherein the metal alloy layers are bonded on the ceramic substrate board by direct bonding.
- 108. (New) The power module according to claim 106, wherein the metal alloy layers are bonded on the ceramic substrate board through a brazing material layer.
- 109. (New) A power module comprising:

a ceramic substrate board;

metal alloy layers consisting essentially of aluminum and of Cu of not less than 1.0% by weight and not more than 2.0% by weight, wherein the metal alloy layers are bonded on both surfaces of the ceramic substrate board; a metal base plate bonded to one of the metal alloy layers; and a semiconductor tip formed on the other of the metal alloy layer,

wherein a Vickers hardness of the metal alloy layer is not less than 25 and not more than 35.

- 110. (New) The power module according to claim 109, wherein the metal alloy layers are bonded on the ceramic substrate board by direct bonding.
- 111. (New) The power module according to claim 109, wherein the metal alloy layers are bonded on the ceramic substrate board through a brazing material layer.
- 112. (New) A power module comprising:
  - a ceramic substrate board;
  - metal alloy layers consisting essentially of aluminum and of Zn of about 2.0% by weight, wherein the metal alloy layers are bonded on both surfaces of the ceramic substrate board;
  - a metal base plate bonded to one of the metal alloy layers; and
  - a semiconductor tip formed on the other of the metal alloy layer,

wherein a Vickers hardness of the metal alloy layer is not less than 25 and not more than 35.

113. (New) The power module according to claim 112, wherein the metal alloy layers are bonded on the ceramic substrate board by direct bonding.

- 114. (New) The power module according to claim 112, wherein the metal alloy layers are bonded on the ceramic substrate board through a brazing material layer.
- 115. (New) A power module comprising:

a ceramic substrate board;

metal alloy layers consisting essentially of aluminum and of Ni of about 0.5% by weight, wherein the metal alloy layers are bonded on both surfaces of the ceramic substrate board;

a metal base plate bonded to one of the metal alloy layers; and a semiconductor tip formed on the other of the metal alloy layer,

wherein a Vickers hardness of the metal alloy layer is not less than 25 and not more than 35.

- 116. (New) The power module according to claim 115, wherein the metal alloy layers are bonded on the ceramic substrate board by direct bonding.
- 117. (New) The power module according to claim 115, wherein the metal alloy layers are bonded on the ceramic substrate board through a brazing material layer.
- 118. (New) A power module comprising:

  a ceramic substrate board;

35.

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metal alloy layers consisting essentially of aluminum and of Mg of not less than 0.2% by weight and not more than 0.5% by weight, wherein the metal alloy layers are bonded on both surfaces of the ceramic substrate board;

a metal base plate bonded to one of the metal alloy layers; and

a semiconductor tip formed on the other of the metal alloy layer,

wherein a Vickers hardness of the metal alloy layer is not less than 25 and not more than

119. (New) A power module comprising:

a ceramic substrate board;

metal alloy layers consisting essentially of aluminum, silicon of about 0.1% by weight, and Cu of about 1.0% by weight, wherein the metal alloy layers are bonded on both surfaces of the ceramic substrate board;

a metal base plate bonded to one of the metal alloy layers; and

a semiconductor tip formed on the other of the metal alloy layer,

wherein a Vickers hardness of the metal alloy layer is not less than 25 and not more than

120. (New) The power module according to claim 119, wherein the metal alloy layers are bonded on the ceramic substrate board by direct bonding.

- 121. (New) The power module according to claim 119, wherein the metal alloy layers are bonded on the ceramic substrate board through a brazing material layer.
- 122. (New) A power module comprising:

a ceramic substrate board:

metal alloy layers consisting essentially of aluminum, Si of about 0.1% by weight,

Cu of about 1.0% by weight, and Mg of about 0.1% by weight, wherein
the metal alloy layers are bonded on both surfaces of the ceramic substrate
board;

a metal base plate bonded to one of the metal alloy layers; and

a semiconductor tip formed on the other of the metal alloy layer,

wherein a Vickers hardness of the metal alloy layer is not less than 25 and not more than 35.

- 123. (New) The power module according to claim 122, wherein the metal alloy layers are bonded on the ceramic substrate board by direct bonding.
- 124. (New) The power module according to claim 123, wherein the metal alloy layers are bonded on the ceramic substrate board through a brazing material layer.